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Exhibitor Introduction (Within 200 words)	 Application Industrial System for PVD and CVD R&D System for PVD and CVD Sputtering System Retrofit (Planar Cathode → Rotary Cathode) Upgrade and Customization History 2016. 04 : Supplied sputter system to Baylor Univ. (TX, USA) 2015. 07 : Registered patent (Sputter system), trademark & design (Minutus[™]) 2015. 07 : ISO9001 certification 2015. 06 : Founded R&D center 2015. 01 : Founded company Creative Solution with Valuable Technology!



	Vacuum deposition system
	1. R&D system
	- MINUTUS [™] : Sputter (Compact size sputter system)
Exhibit Description	- MINUTUS eX series : Sputter, RIE, PECVD, PAALD
(Within 200 wors)	- PATEO series : Sputter, Evaporator, RIE, PECVD
	2. Industrial system
	- INLINE system
	- CLUSTER system
	- BATCH system
Exhibit Product	Vacuum Equipment poster & brochure